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**Reinmuth**

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(54) **MICRO-ELECTROMECHANICAL REFLECTOR AND METHOD FOR MANUFACTURING A MICRO-ELECTROMECHANICAL REFLECTOR**

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See application file for complete search history.

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(57) **ABSTRACT**

(51) **Int. Cl.**  
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A micro-electromechanical reflector is described including an electrode substrate having a first surface and a second surface, which is opposite to the first surface, on whose first surface a carrier layer is situated, a plurality of electrode recesses, which are introduced under the carrier layer from the first surface into the electrode substrate, a plurality of second electrode recesses, which are introduced from the second surface into the electrode substrate, at least one torsion spring structure which is formed in the carrier layer over one of the first electrode recesses, a carrier substrate, which is attached to the second surface of the electrode substrate, and a reflector surface, which is situated on the carrier layer.

(52) **U.S. Cl.**  
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(58) **Field of Classification Search**  
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**10 Claims, 14 Drawing Sheets**

